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**Amendments to the Claims**

Please amend Claims 2, 10, 11 and 32. The Claim Listing below will replace all prior versions of the claims in the application:

**Claim Listing**

1. (Canceled)
2. (Currently Amended) A method for generating and evaluating property estimation grids for use with a dielectrometer that provides at least two effective field penetration depths for measuring preselected properties of a material, said method comprising:
  - a) defining electrical, physical, and geometric properties for the material, including preselected properties of the material;
  - b) defining operating point parameters for the material properties and an electrode geometry, electrode configuration, substrate material and dimensions, and electrical source excitation for the dielectrometer;
  - c) inputting the material properties, the operating point parameters, and the dielectrometer electrode substrate geometry, configuration and source excitation into a model to compute an input/output a terminal relation value for each penetration depth;
  - d) recording in a database the terminal relation value for each penetration depth relative to the material properties as a property estimation grid point;
  - e) adjusting the preselected material properties ~~of the material~~ and repeating steps (c) and (d) for remaining property estimation grid points; and
  - f) analyzing a property estimation grid to determine fitness of the property estimation grid for a particular measurement.
3. (Previously Presented) A method as claimed in Claim 2 wherein the terminal relation value of step (c) is at least one of: transcapacitance value, transconductance value, transadmittance value, transimpedance value, self-admittance value, self-impedance value, and complex gain.

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4. (Canceled)
5. (Previously Presented) A method as claimed in Claim 2 wherein the material comprises a liquid mixture of unknown properties.
6. (Previously Presented) A method as claimed in Claim 2 further comprising: the step of plotting terminal relation values on a single or multidimensional grid.
7. (Previously Presented) A method as claimed in Claim 2 wherein the grid points represent magnitude and phase measurements for a single wavelength dielectric sensor.
8. (Previously Presented) A method as claimed in Claim 2 wherein the property estimation grids are magnitude-magnitude grids with the magnitudes determined from different field penetration depths.
9. (Previously Presented) A method as claimed in Claim 8 wherein the magnitude-magnitude grids are used for measurements performed on a semi-insulating material.
10. (Currently Amended) A method for generating and evaluating property estimation grids for use with a dielectrometer ~~that provides at least two effective field penetration depths~~ for measuring preselected properties of a material, said method comprising:
  - a) defining electrical, physical, and geometric properties for the material, including preselected properties of the material;
  - b) defining operating point parameters for the material properties and an electrode geometry, electrode configuration, substrate material and dimensions, and electrical source excitation for the dielectrometer;
  - c) inputting the material properties, the operating point parameters, and the dielectrometer electrode substrate geometry, configuration and source excitation

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into a model to compute ~~an input/output~~ a terminal relation value for each of a dielectric sensor and a non-dielectric sensor;

- d) recording in a database the terminal relation value for each penetration depth sensor relative to the material properties as a property estimation grid point;
- e) adjusting the preselected material properties of the material and repeating steps (c) and (d) for remaining property estimation grid points; and
- f) analyzing a property estimation grid to determine fitness of the property estimation grid for a particular measurement, one axis of a property estimation grid representing a magnitude or phase measured with a dielectric sensor and a second axis representing a parameter measured with a non-dielectric sensor.

- 11. (Currently Amended) A method as claimed in Claim 2 wherein one or more of the operating point parameters for the material properties in steps (b) and (c) is temperature dependent and wherein variations in the temperature are used to alter the at least one operating point parameter.
- 12. (Previously Presented) A method as claimed in Claim 2, further comprising:
  - computing Jacobian elements which are measures of variation in computed terminal relation values due to variation in the preselected material properties;
  - computing a singular value decomposition for the Jacobian elements to obtain singular values, singular vectors and condition numbers of the Jacobian elements;
  - evaluating at least one of: the dielectrometer electrode, substrate structures and operating point using the singular values, singular vectors, and the condition numbers for material property estimate requirements;
  - adjusting at least one of: the dielectrometer operating point parameters, electrode geometry, configuration, substrate material and geometry, and the source excitation; and
  - repeating steps (b) - (f) until material property estimate requirements are achieved.
- 13. (Previously Presented) A method as claimed in Claim 12 wherein the singular values, singular vectors, and the condition numbers are stored with grid points.

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14. (Previously Presented) A method as claimed in Claim 12, further comprising:  
converting each sensed electromagnetic response into a transadmittance or transimpedance magnitude and phase or equivalently into real and imaginary parts.
15. (Previously Presented) A method as claimed in Claim 2 wherein the material under test is composed at least in part of a viscous material.
16. (Previously Presented) A method as claimed in Claim 15 wherein the viscous material is curable.
17. (Previously Presented) A method as claimed in Claim 15 wherein the material is monitored as part of a quality control process.
- 18-21. (Canceled)
22. (Withdrawn) A sensor comprising:  
a first and a second interdigital conductors; and  
a meandering conductor which has elements which parallel the first interdigital conductor.
23. (Withdrawn) A sensor of claim 22 wherein the elements of the meandering conductor are equally spaced on either side of each of the digits of the first interdigital conductor.
24. (Withdrawn) A sensor of claim 23 wherein the ratio of the distance between the digits of the first interdigital conductor and the elements of the meandering conductor and the distance between the digits of the first interdigital conductor and the digits of the second interdigital conductor is approximately 1.6.
25. (Withdrawn) A sensor of claim 23 further comprising a switching device for selecting one of the first interdigital conductor, the second interdigital conductor and the meandering

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conductor as a driven electrode, selecting another of the first interdigital conductor, the second interdigital conductor and the meandering conductor as a sensing electrode and selecting the last as a guard electrode.

26-27. (Canceled)

28. (Withdrawn) A method of determining properties of material under test comprising the steps of:

- providing a pair of substantially identical sensors;
- immersing the material under test in a first liquid dielectric;
- pressing one of the sensors against the material under test;
- immersing the other sensor in the first liquid dielectric and spaced from the material under test;
- measuring the capacitance of each of the two sensors;
- adding a second miscible liquid with a higher dielectric permittivity to the first liquid; and
- comparing the capacitance of the sensors as the second liquid is added.

29. (Withdrawn) A method of determining properties of material under test of claim 28 wherein when the two capacitances of the two sensors become identical, the liquid mixture dielectric permittivity equals the dielectric permittivity of the material under test.

30. (Previously Presented) A method as claimed in Claim 2 wherein the property estimation grids are phase-phase grids.

31. (Previously Presented) A method as claimed in Claim 10 wherein the parameter measured with a non-dielectric sensor is a thickness.

32. (Currently Amended) A method as claimed in Claim 10 wherein one or more of operating point parameters for the material properties in steps (b) and (c) are temperature dependent

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and wherein variations in the temperature are used to alter the at least one operating point parameter.